

Amendments to the Specification:

Please amend paragraph [0021] as follows:

[0021] One skilled in the art would understand that the fluorocarbon gases serve as etchants that react with the deposits to produce cleaning by-products. Such byproducts can be removed from the chamber in step 170 through gas outlets in the chamber. In certain preferred embodiments of the process 100, it is desirable to use fluorocarbon gases having a higher reactivity or a higher fluorine content than hexafluoroethane. Such characteristics advantageously allow the use of reduced quantities of cleaning gas. In some preferred embodiment, for example, the fluorocarbon gas is selected from the group consisting of: ~~octofluoropentane (C₃F₈)~~; ~~octofluorocyclobutane (C₄F₈)~~; and ~~octafluorotetrahydrofuran (C₄F₈O)~~.